

## Evo 18 SEM Facility

**EVO 18 SEM** is the scanning electron microscope from **Carl Zeiss**, Germany

### *System Specification*

- **Filament** : Tungsten
- **Secondary e-image resolution** : 50 NM  
(Depends on sample)
- **BSD Detector** : Available
- **Tilt** : 0 - 60 Degree
- **Rotation** : 360 Degree
- **EHT** : 200V - 30KV
- **Magnification** : Up to 50K ~ 100K (Depends on sample)



### *Process Capabilities*

- **Imaging Modes** : Surface & Cross-Sectional
- **Sample Holder** : Maximum 9 stubs (~1 CM Dia.) can be mounted
- **Substrates Used** : Si, Glass, Sapphire, Ge
- **Substrate Size** :
  - (2 x 2 x Z)MM to (10 x 10 x Z)MM [For surface imaging]
  - (4 x 4 x Z)MM to (8 x 8 x Z)MM [For cross-sectional imaging]
  - where Z is the variable substrate thickness (it can vary from 200 microns to 2 mm, depending on the substrate type like: Si / glass substrates).